Appl. No. 10/815,593 Steven K. Hansen, et al.

Amdt. Dated January 3, 2007

Response to Office Action of August 3, 2006

Amendment to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

1. (Currently Amended) A method for marking a target media using a microlaser which upon reaching an absorbed power saturation threshold emits a high peak power pulse of light, said method comprising:

driving the microlaser at a simmer power level selected to maintain the microlaser below the saturation threshold and to limit the activation time of the microlaser;

directing the microlaser at the target media on which the mark is to be made;

increasing the power applied to the microlaser to the saturation threshold to cause the microlaser to emit a pulse of light for forming the mark; and

decreasing the power applied to the microlaser to the simmer level after the mark is formed; and

monitoring a current, a voltage, and a temperature feedback of the microlaser to maintain the microlaser at a predetermined power level while in the simmer mode.

- 2. (Original) The method of claim 1, including directing said pulse of light emitted by said saturable absorber along a path toward the target media.
- 3. (Original) The method of claim 1, including directing said pulse of light with at least one mirror.

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4. (Original) The method of claim 3, in which said at least one mirror is pivotally mounted, and directing said pulse of light includes pivoting said mirror.

5. (Original) The method of claim 1, including directing said pulse of light through a fiber optic material.

6. (Original) The method of claim 2, including feeding said target media into the path of said pulse of light.

7. (Original) The method of claim 1, in which said predetermined level below the saturation threshold is at least 50% of the saturation threshold.

8. (Original) The method of operating a laser marking/imaging system as in claim 1, in which said predetermined level below the saturation threshold is at least 90% of the saturation threshold.

9. (Original) The method of claim 1, wherein the microlaser is a passively Q-switched laser.

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10. (Currently Amended) A laser marking/imaging system comprising:

a passively Q-switched microlaser having a saturable absorber which upon reaching a

saturation power threshold emits a pulse of light through an optical output;

control circuitry electrically connected to said microlaser to monitor a current, a

voltage, and a temperature feedback and to maintain the microlaser in a simmer mode below

said saturation power threshold when not providing a mark, and for driving the microlaser to

the saturation power threshold to emit a pulse of light when a mark is required, to a cooling

system disposed to cool the microlaser, and to a photodiode electrically coupled to the

microlaser to provide feedback when the microlaser is activated to monitor the repetition rate

of the microlaser; and

a guidance mechanism which directs said pulse of light from said optical output along

a path toward an image receiving target when said control circuit is in said lasing mode.

11. (Original) The laser marking/imaging system as in claim 10, in which said

guidance mechanism includes a flexible fiber optic material having an input end which

receives said pulse of light from said optical output and an output end through which said

pulse of light exits said fiber optic material.

12. (Original) The laser marking/imaging system as in claim 11, in which said

output end of said fiber optic material is mounted to a movable carriage disposed adjacent

said image receiving target.

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13. (Original) The laser marking/imaging system as in claim 10, in which said

guidance system includes at least one mirror which directs said pulse of light from said

optical output.

14. (Original) The laser marking/imaging system as in claim 13, in which said at

least one mirror is pivotally mounted.

15. (Original) The laser marking/imaging system as in claim 10, including a

media feed assembly feeding an image receiving target into the path of said pulse of light.

16. (Original) The laser marking/imaging system as in claim 15, in which said

media feed assembly includes a platen supporting the image receiving target in the path of

said pulse of light.

17. (Currently Amended) The laser marking/imaging system as in claim 16, in

which at least one of said platen and at least a portion of said guidance system is movable to

vary the distance between said platen and said at least a portion of said guidance system

distance.

18. (Original) The laser marking/imaging system as in claim 10, in which said

guidance system includes a carriage movable relative to said optical output, and said carriage

supports structure which directs said pulse of light toward the image receiving target.

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19. (Original) The laser marking/imaging system as in claim 10, including a

platform disposed in the path of said light pulse for supporting the image receiving target in

the path of said light pulse.

20. (Original) The laser marking/imaging system as in claim 19, in which said

platform includes at least one degree of freedom.

21. (Original) The laser marking/imaging system as in claim 10, in which said

control circuitry is disposed in an electrical enclosure and said guidance mechanism is

disposed in a printing enclosure separated from said electrical enclosure.

22. (Original) The laser marking/imaging system as in claim 21, in which said

electrical enclosure and said printing enclosure are separated by a common wall.

23. (Original) The laser/imaging system as in claim 10, in which power provided

to said microlaser is maintained at a power level of at least 50% of said power threshold in

said simmer mode.

24. (Original) The laser/imaging system as in claim 10, in which power provided

to said microlaser is maintained at a power level of at least 90% of said power threshold in

said simmer mode.

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25. (Original) The laser/imaging system as in claim 10, wherein said control

circuitry is further connected to a cooling system to drive the cooling system and to a

temperature sensor to monitor an actual temperature and wherein the control circuit further

comprises a controller for driving the cooling system.

26. (Currently Amended) The laser imaging system as in claim 25, wherein the

controller employs a proportional-integral-differential loop to drive the cooling system

microlaser.

27. (Original) The laser imaging system as in claim 25, further comprising a

photodiode electrically coupled to the microlaser and to the controller, the photodiode

providing feedback when the microlaser is activated wherein the controller monitors the

repetition rate of the microlaser.

28 - 31. (Cancelled)

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32. (New) A method for marking a target media using a microlaser which upon

reaching an absorbed power saturation threshold emits a high peak power pulse of light, said

method comprising:

(a) driving the microlaser at a simmer power level selected to maintain the microlaser

below the saturation threshold and to limit the activation time of the microlaser;

(b) monitoring a current, a voltage, and a temperature feedback and adjusting the

power applied to the microlaser to maintain the microlaser at a predetermined power level;

(c) repeating steps a - b until a command has been received to form a mark;

(d) directing the microlaser at the target media on which the mark is to be made when

the command is received and increasing the power applied to the microlaser to the saturation

threshold to cause the microlaser to emit a pulse of light for forming the mark; and

(f) decreasing the power applied to the microlaser to the simmer level after the mark

is formed and returning to step (a).

33. (New) The method of claim 33, wherein step (b) further comprises the step of

cooling the microlaser to maintain the microlaser within predetermined operating parameters

in the simmer mode.

34. (New) The method of claim 33, wherein step (f) comprises the step of

monitoring a number of pulses applied to form the mark.

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